

In the Claims

1. (currently amended) Arrangement comprising a support body and a substrate holder which is supported thereon and driven in rotation, ~~the~~ a gas bearing and ~~the~~ a rotary drive being formed by means of gas flowing into the separating gap between support body and substrate holder from nozzles, characterized in that the support body and the substrate holder are formed as rings, and the support body includes a ring bead which projects into a ring recess in the substrate holder.
2. (currently amended) Arrangement according to Claim 1 ~~or in particular according thereto~~, characterized in that the rings rest on top of one another in a self-centering fashion.
3. (cancelled)
4. (currently amended) Arrangement according to Claim 1 ~~or in particular according thereto~~, characterized in that the substrate is supported on the ring which is driven in rotation only by means of its edge.
5. (currently amended) Arrangement according to Claim 1 ~~or in particular according thereto~~, characterized in that the substrate rests on the ring with minimal contact, preferably only on the tips of needle-like protuberances.
6. (currently amended) Arrangement according to Claim 1 ~~or in particular according thereto~~, characterized in that the nozzles open out into arcuate grooves, ~~in particular arcuate grooves.~~

7. (currently amended) Arrangement according to Claim 1 ~~or in particular according thereto~~, characterized in that the nozzles open out into arcuate grooves with alternating preferred directions of gas flow streams, said streams flowing in opposite directions ~~inside them alternate~~.

8. (currently amended) Arrangement according to Claim 1 ~~or in particular according thereto~~, characterized by oppositely directed driving gas streams for rotationally bearing and rotationally driving the rotating ring.

9. (currently amended) Arrangement according to Claim 1 ~~or in particular according thereto~~, characterized in that the substrate ~~is~~ can be radiation-heated from below through the rings.

10. (currently amended) Arrangement according to Claim 1 ~~or in particular according thereto~~, characterized in that the support body and/or the substrate holder consist of quartz or ceramic material.

11. (currently amended) Arrangement according to Claim 10 ~~or in particular according thereto~~, characterized in that the rotationally driven ring has a low heat absorption.

12. (currently amended) Arrangement according to Claim 11 ~~or in particular according thereto~~, characterized in that the arrangement is part of a device for the heat treatment of semiconductor wafers.

13. (currently amended) Device for the in particular rapid heat treatment of ~~in particular flat objects, such as semiconductors, glass or metal substrates,~~ having a support body and a substrate holder which is supported thereby in such a manner that it can be

driven in rotation and on which the flat object can be placed, it being possible to produce a gas cushion beneath the substrate holder by means of gas which emerges from nozzles which open out into a separating gap between support body and holding body, on which gas cushion the substrate holder rests in such a manner that it is driven in rotation by directed gas streams, characterized in that the support body and the substrate holder are formed as rings, the support body includes a ring bead which projects into a ring recess in the substrate holder, the support body and/or the substrate holder consist of quartz or ceramic material, the rotationally driven ring has a low heat absorption, and the arrangement is part of a device for the heat treatment of semiconductor wafers. ~~and the device is formed in particular according to Claim 12.~~

14. (new) Arrangement according to Claim 1, wherein the nozzles open out into the separating gap and open out into grooves.

15. (new) Arrangement according to Claim 14, wherein said grooves are formed in the mating surface of said support body opposite the mating surface of said substrate holder.

16. (new) Arrangement according to Claim 15, wherein each nozzle opens out into the proximal end of a corresponding groove.

17. (new) Arrangement according to Claim 16, wherein gas emerging from each nozzle flows in a preferred direction from the proximal end of each groove to the distal end of each groove.

18. (new) Arrangement according to Claim 17, wherein said grooves are distributed on the surface of said support body such that there are alternating preferred directions of gas flows.

19. (new) Arrangement according to Claim 18, wherein said preferred directions are opposite directions.

20. (new) Arrangement according to Claim 19, wherein a portion of said grooves are formed in the surface of said ring bead.

21. (new) Arrangement according to Claim 20, wherein said grooves are arcuate grooves.